



## MPGD &amp; Active媒質TPC2020研究会

Saturday, December 26, 2020

Session 6 (2:45 PM - 3:40 PM)

-Conveners: Atsuhiko OCHI

time	[id] title	presenter
2:45☒PM	[19] 表面抵抗率の異なるDLCを用いたresistive $\mu$ -picの基本性能の評価	谷口 大悟
3:10☒PM	[20] A novel technique for the measurement of the avalanche fluctuation of a GEM stack using a gating foil	弓野 圭太
3:35☒PM	[21] Closing remarks	MIUCHI, Kentaro